

Projects for FCC-ee Vertex Detectors

FCC-week 2026

Helsinki

June 8-12, 2026

Dominik Dannheim (CERN)

Outline

- FCC-ee vertex-detector requirements
- Vertex-detector concepts
- Detector R&D projects
- Conclusions

Disclaimer:

- Not a complete overview, showing only **few examples**
 - Focus on specific R&D for FCC-ee / CEPC **vertex-detector**
- not covering the (many!) developments for outer tracking + timing layers

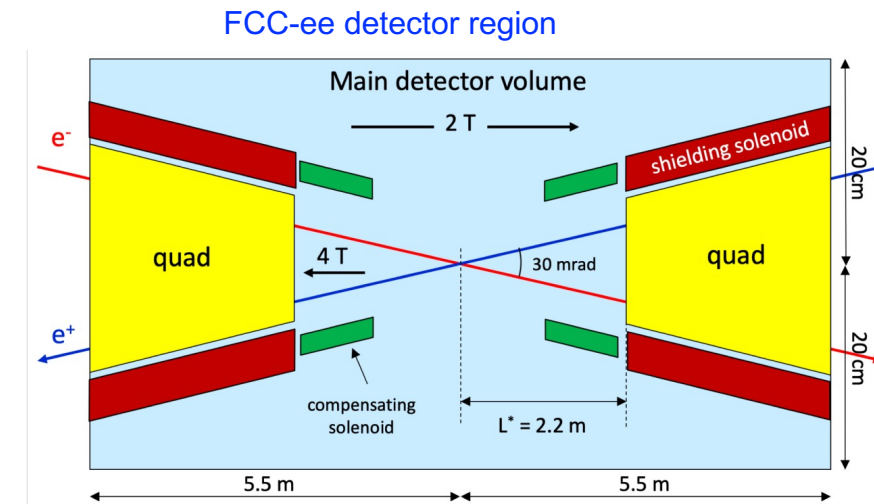
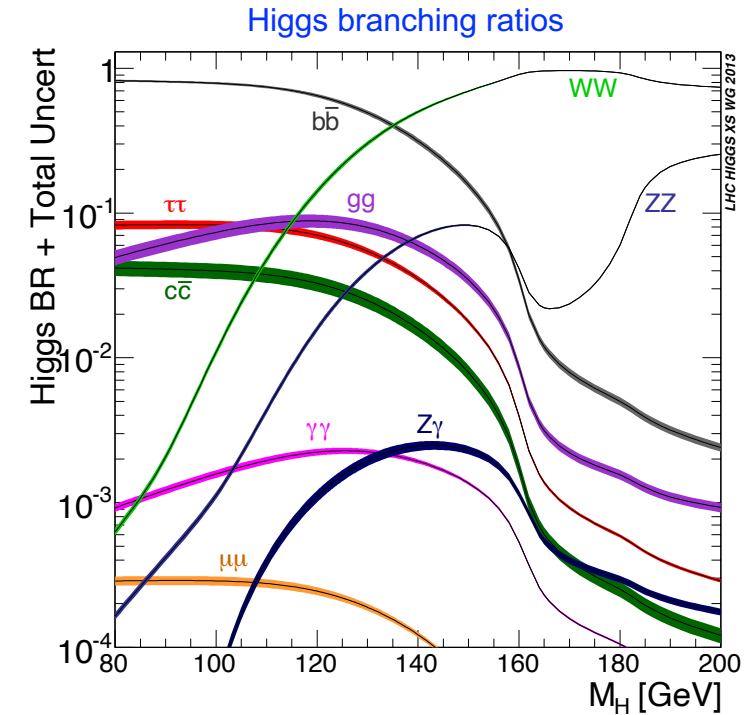
Physics requirements and experimental constraints

• Physics goals:

- Precision **Higgs** / **EW** / **top** measurements
- Direct/indirect **BSM searches**
- Requires excellent Flavour tagging (c, b), life-time measurements
 - Vertex resolution: $\sigma(d0) \sim 5 \oplus 15 / (p[\text{GeV}] \sin^{3/2} \theta) \mu\text{m}$
 - single-plane resolution $\sim 3 \mu\text{m}$
 - low material budget $< 0.2\% X_0$ per layer → low power+ air-flow cooling
- Pile-up / background rejection
 - **low-angle coverage**, **timing**

Experimental constraints:

- 30 mrad crossing angle, focusing quadrupoles inside detector
- B-field limited to ~ 2 Tesla
- High rate of physics events (up to 100 kHz, bx spacing down to 30 ns)
- **Integration time $< 1 \mu\text{s}$** for occupancy and pile-up (**30 ns @ Z-pole**)
- Fast detector frontend and DAQ
- Main backgrounds:
 - synchr. rad. (requires **shielding**) + incoherent pairs (up to $\sim 200 \text{ MHz/cm}^2$)
- Continuous collisions (100% duty cycle)
- **Pulsed powering not possible**
- Moderate radiation exposure:
 - NIEL: $< 10^{14} \text{ neq/cm}^2/\text{y}$** ; **TID: $< 100 \text{ kGy / year}$**

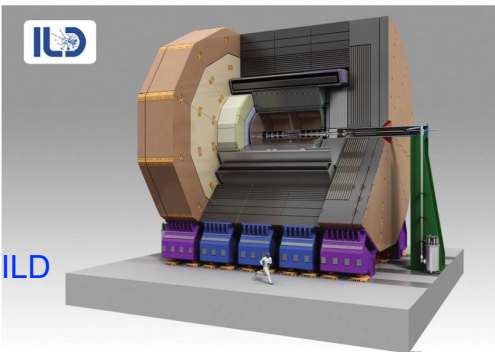


Detector concepts

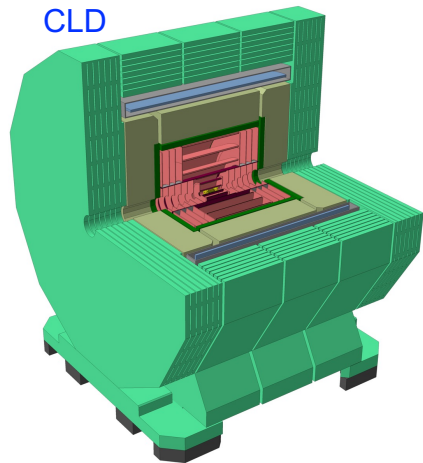
Collider	FCC-ee				CEPC	
Detector Concept	FCC-ee ILD	CLD	FCC-ee IDEA	ALLEGRO	CEPC baseline	CEPC IDEA
B-field [T]	2	2	2	2	3	2
Vertex inner radius [mm]	13	13	14	14	11	11
Tracker out. radius [m]	1.8	2.2	2.0	2.0	1.81	2.05
Vertex	Si-pixel	Si-pixel	Si-pixel	Si-pixel	Si-pixel	Si-pixel
Tracker	TPC/ Si strips	Si-pixel	DC/ Si-strips	DC/Si-strips or Si-pixel	TPC/Si-strips or Si-strips	DC/ Si-strips

https://europeanstrategyupdate.web.cern.ch/sites/default/files/Submitted_Input_2025.05.26.pdf

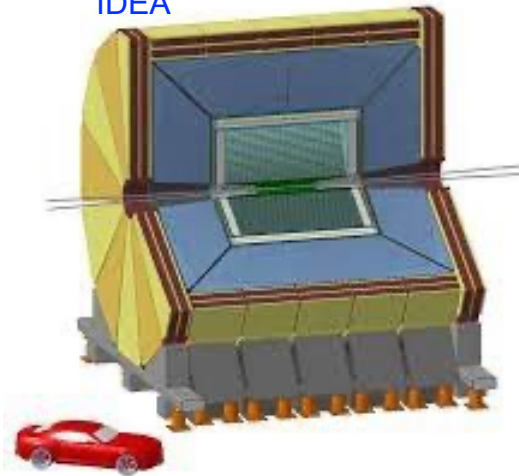
[arXiv:1811.10545](https://arxiv.org/abs/1811.10545)



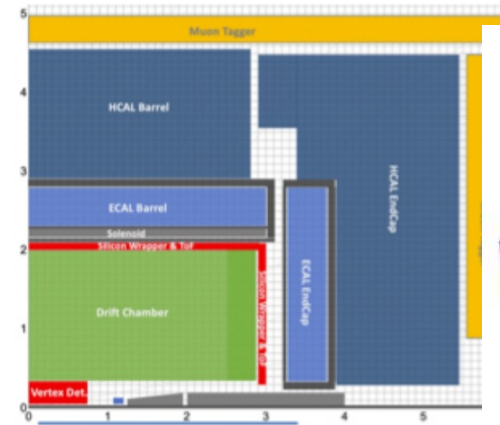
CLD



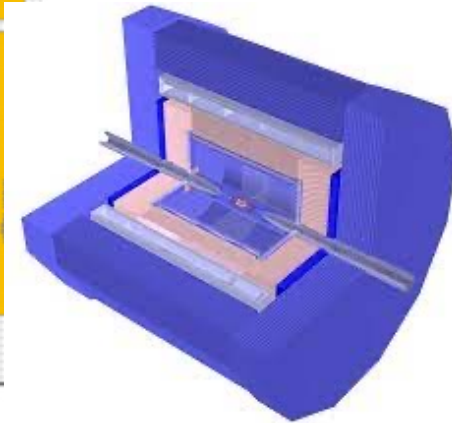
IDEA



ALLEGRO



CEPC baseline



Detector concepts

Collider	FCC-ee				CEPC	
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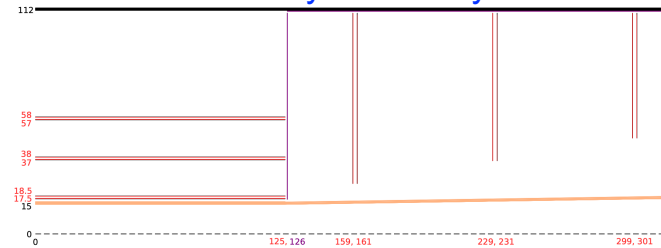
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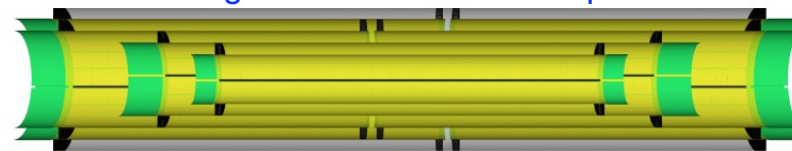
All concepts contain **MAPS vertex detectors**:

- 5-6 layers in doublets or singlets
- Different layouts under consideration:
 - Barrel + endcap
 - Barrel-only (stitched bent silicon, like in ALICE ITS3)

CLD double-layer VXD layout

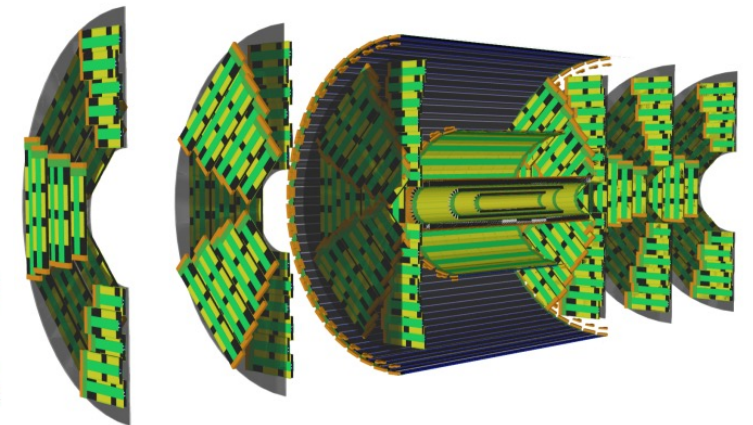


Ultra-light FCC-ee VXD concept



<https://pos.sissa.it/476/1062/>

IDEA/ALLEGRO VXD



ARCADIA fully-depleted 110 nm MAPS

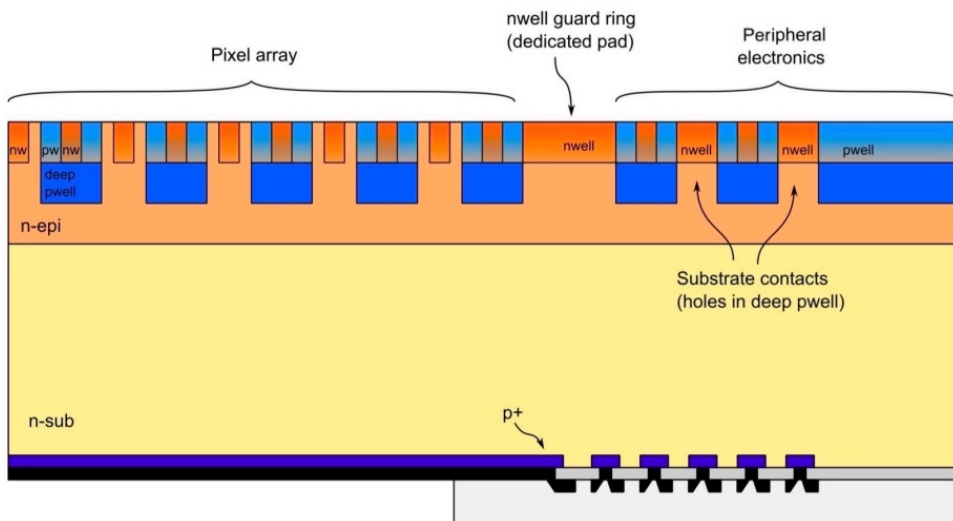
ARCADIA collaboration between [INFN](#) and [L-Foundry](#)

- R&D on semiconductor [sensor technology](#), IP-core design and ASICs, advanced DAQs
- Target applications include [FCC-ee \(IDEA\) vertex](#) and tracker
- Using L-Foundry [110 nm MAPS](#) process
 - backside biasing for full depletion
 - Thickness 50-700 μm \rightarrow large signals, charge sharing
 - Various processing options, including high-resistivity substrates and backside implantations

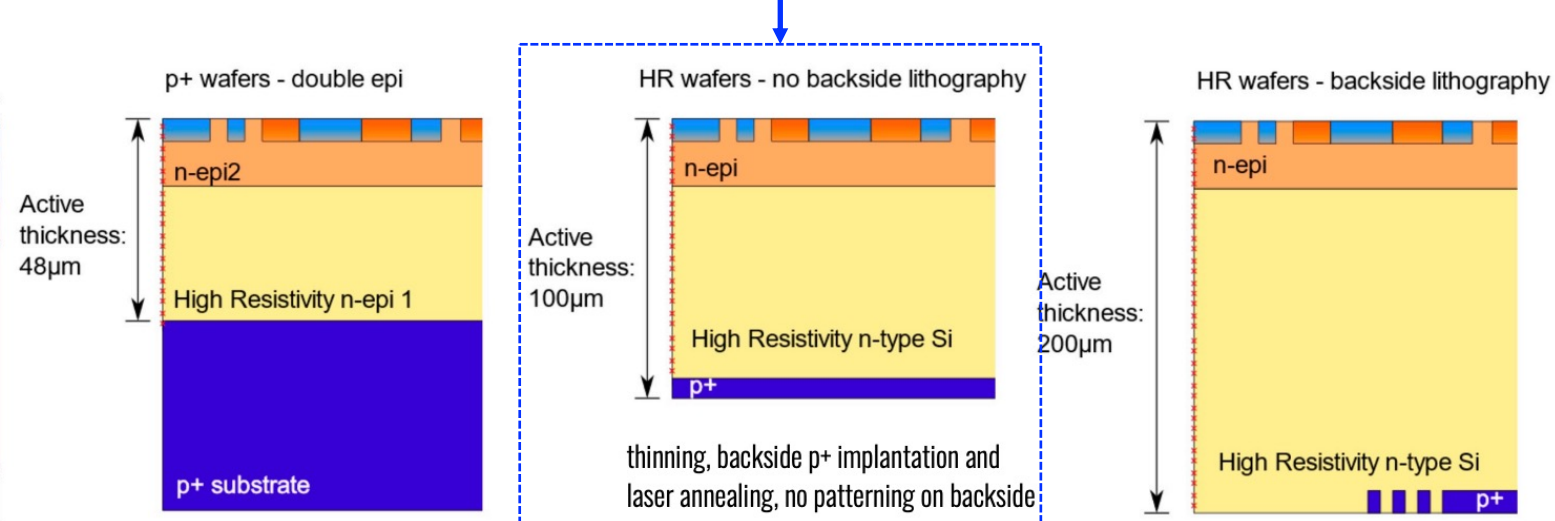
ARCADIA



Istituto Nazionale di Fisica Nucleare



Process used for FCC-ee vertex R&D

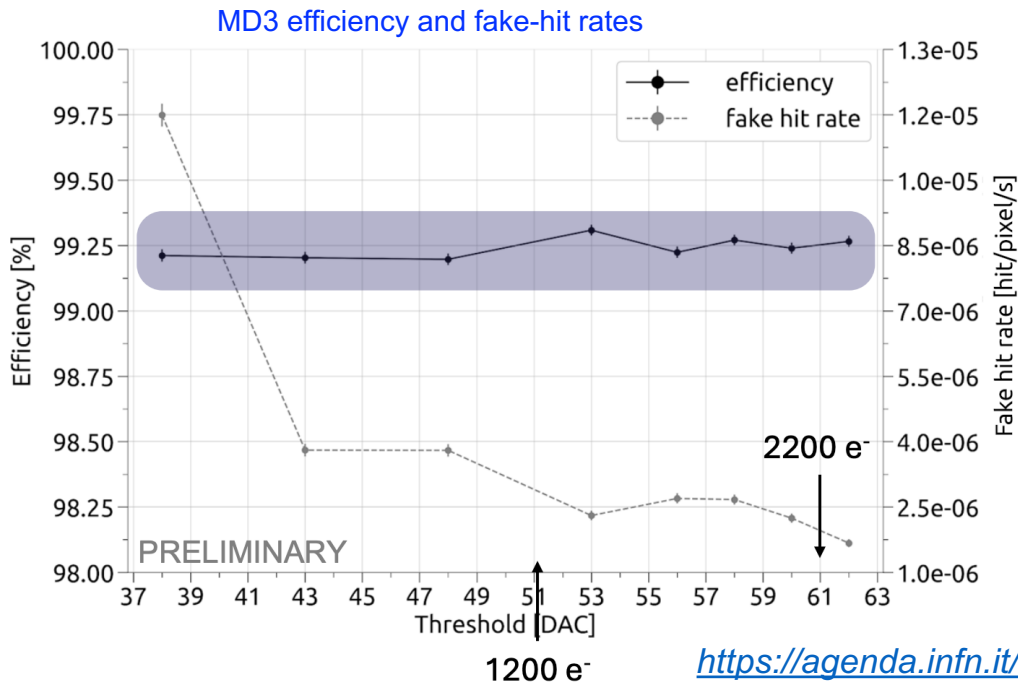
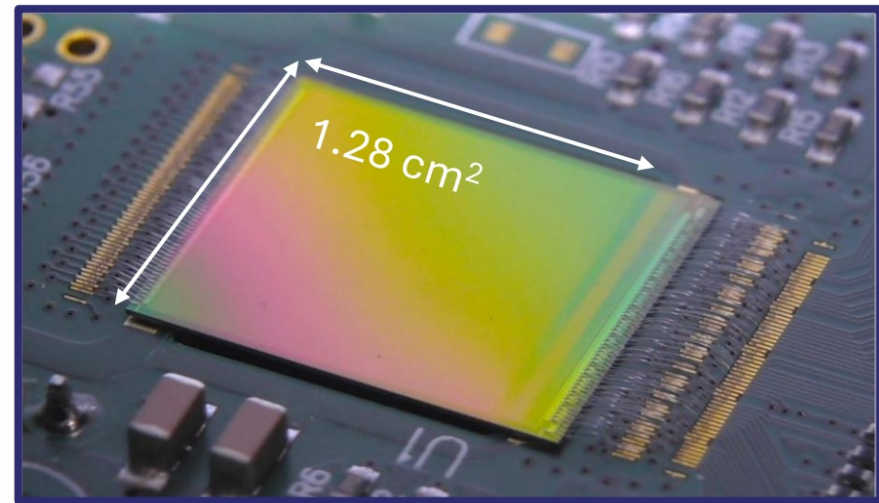


<https://agenda.infn.it/event/47923/contributions/276340/>

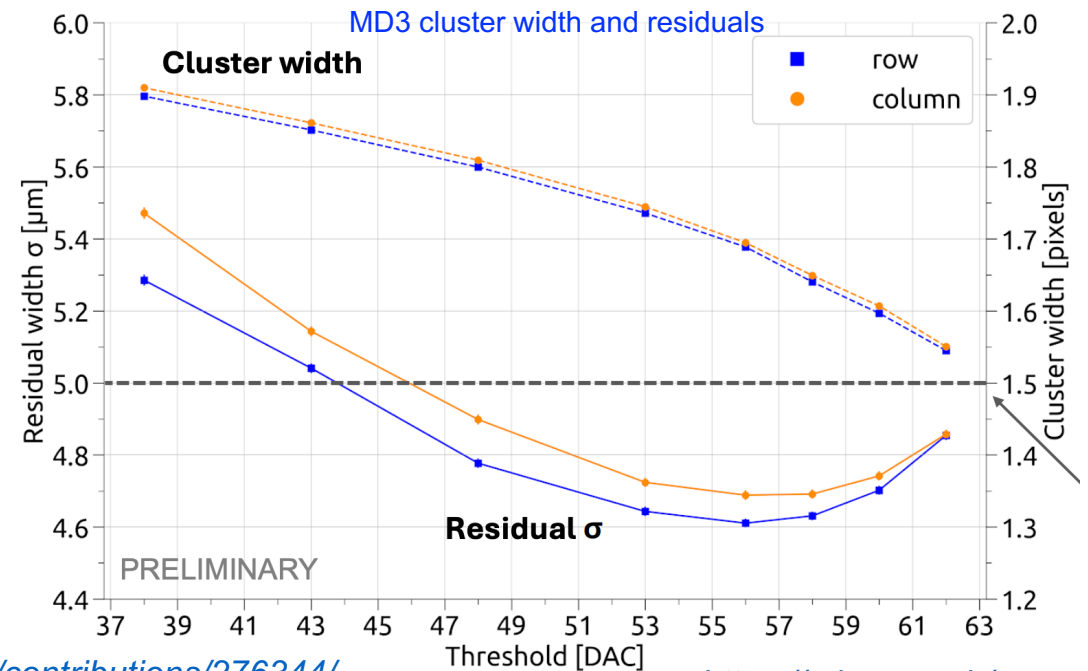
ARCADIA MD3 demonstrator

First full-size prototype **ARCADIA MD3**

- 512 x 512 pixels, 25 μm pitch, 50-200 μm active thickness
- data-driven binary r/o, 30 mW/cm^2, 100 $\text{MHz/cm}^2</math> rate$
- Encouraging lab and test-beam characterization results:
 - Noise $\sim 30 e^-$
 - Efficiency >99%
 - Thick active region and low threshold range
→ significant charge sharing
 - Spatial resolution: minimum residual width of 4.6 μm with 1D average cluster width of about 1.6 pixels



<https://agenda.infn.it/event/47923/contributions/276344/>



<https://cds.cern.ch/record/2954917/>

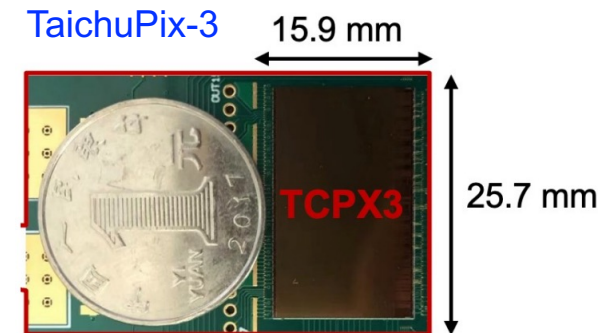
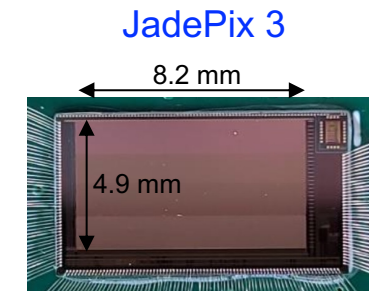
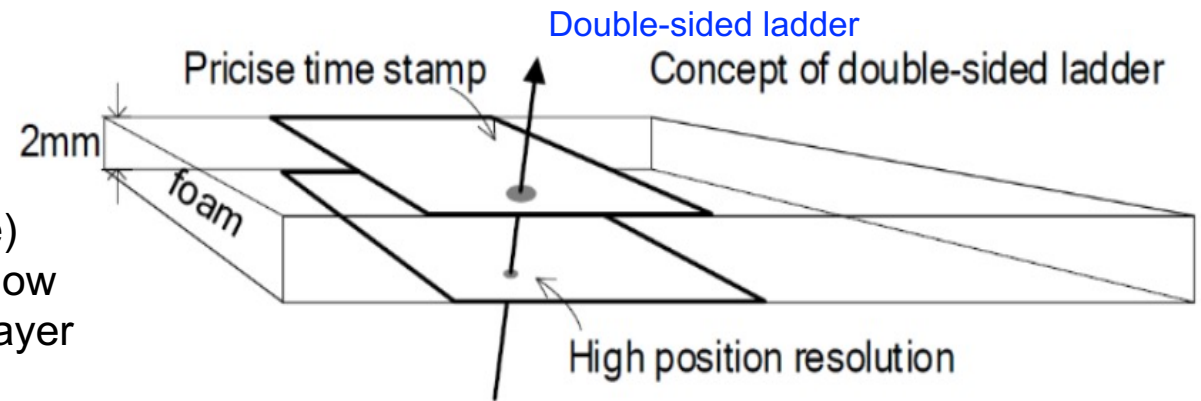
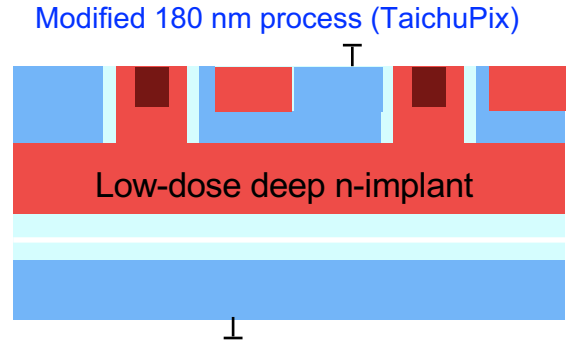
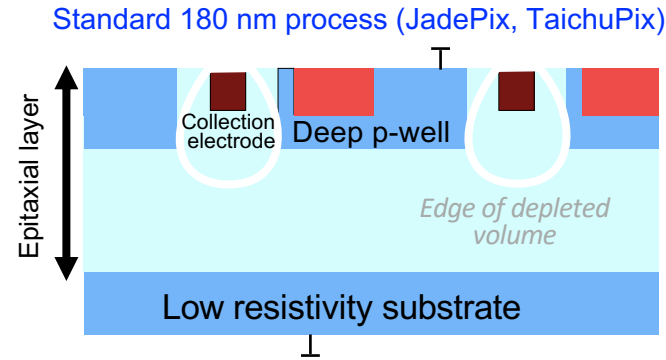
CEPC 180 nm MAPS vertex-detector project

CEPC vertex-detector project

- IHEP Beijing: Chip designs, electronics, DAQ and prototype assembly
- IPHC/CNRS: Collaboration in framework of FCPPL, BELLE II upgrade
- IFAE: Collaboration in Taichu chip design
- ShanDong U.: Stitching chip design, Taichu chip design
- CCNU: Jadxpix chip design
- Northwestern Polytechnical U. : Taichu Chip design
- Nanchang U. : Taichu chip design
- Nanjing U. : testbeam study

- Main target: **CEPC** vertex detector (very similar specs as FCC-ee)
- Using **TJ 180 nm** standard/modified CMOS imaging process for now
 - Small-collection electrode + 20 μm high-resistivity epitaxial layer
 - Plan to move to **TPSCo 65 nm** for final chips
- Considering **separate layers** for timing ($\sim 1 \mu\text{s}$) + position resolution ($\leq 3 \mu\text{m}$)
- Baseline for inner vertex layer: **bent stitched silicon** (like ALICE ITS3)
- Several prototypes, focusing on different aspects
 - JadePix-3 \rightarrow small prototypes: $23 \times 16 \mu\text{m}^2$ pitch, rolling shutter r/o, low power, **high spatial resolution**
 - TaichuPix-3 \rightarrow full-size prototypes: $25 \mu\text{m} \times 25 \mu\text{m}^2$ pitch, hit-driven r/o, high data rate (**36 MHz/cm²**)

See also presentation on **CEPC detector R&D** by Joao on Wednesday



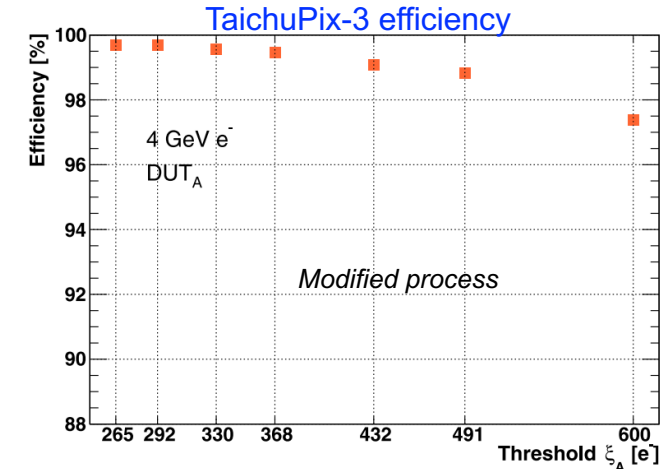
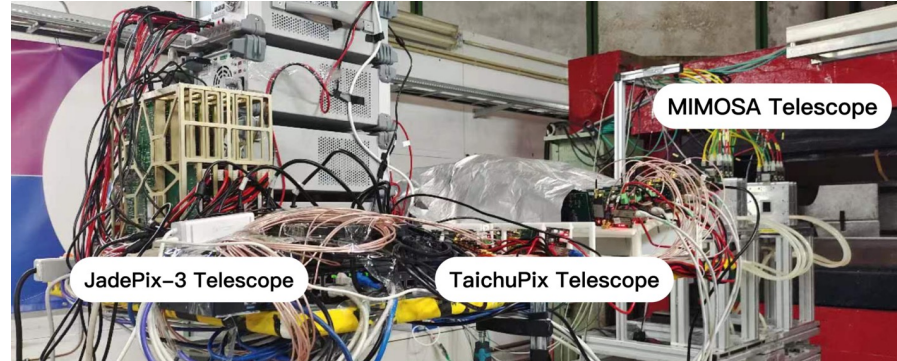
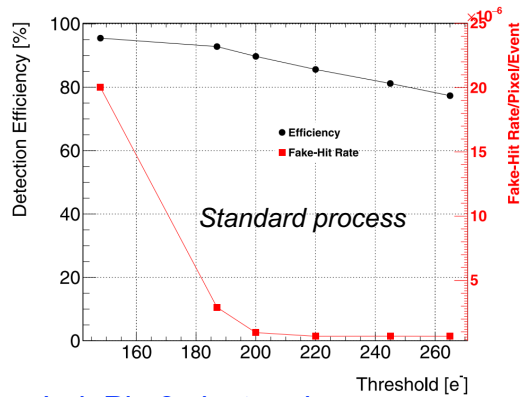
<https://indico.cern.ch/event/1439336/contributions/6242103>

CEPC vertex detector – beam-test results from prototypes

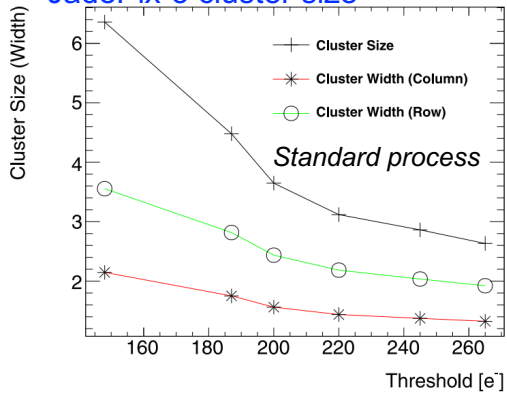
Several test-beam campaigns with Jadepix-3 and TaichuPix-3 prototypes in beam-telescope configuration

- Testing **sensor performance** and **system aspects** of multi-plane detector system
- Achievable position resolution above target of $3\ \mu\text{m}$

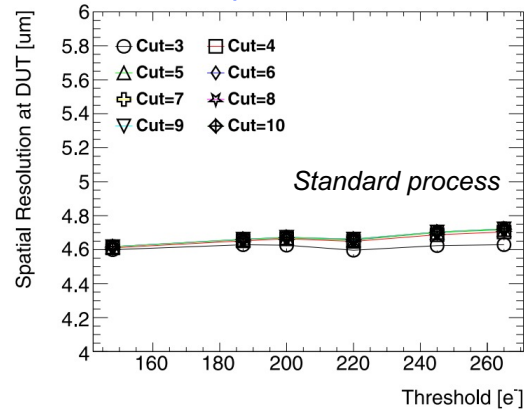
JadePix-3 efficiency + fake-hit rate



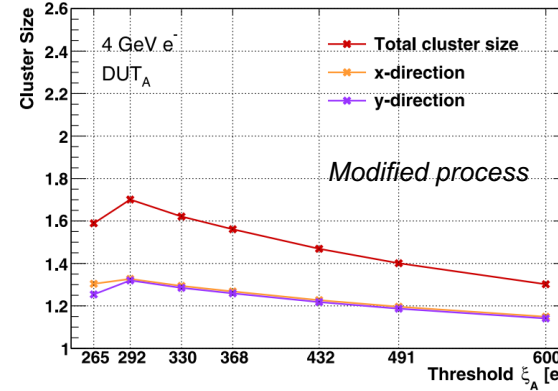
JadePix-3 cluster size



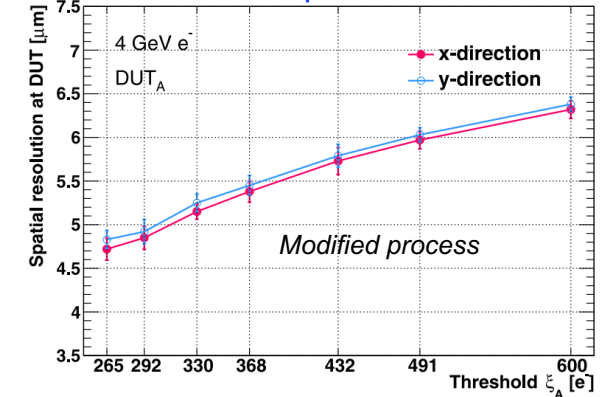
JadePix-3 position resolution



TaichuPix-3 cluster size



TaichuPix-3 position resolution



JadePix-3 ($23 \times 16\ \mu\text{m}^2$ pitch)

- Efficiency **>90%** for negligible fake-hit rate
- Significant charge sharing → multi-pixel clusters
- binary-resolution limit achieved: $6.0\ \mu\text{m} \times 4.6\ \mu\text{m}$

TaichuPix-3 ($25 \times 25\ \mu\text{m}^2$ pitch)

- Efficiency **>99.5%** for negligible fake-hit rate
- Significant charge sharing → multi-pixel clusters
- Resolution better than binary limit: $\sim 4.5\text{-}5\ \mu\text{m}$
- Better performance with modified process

<https://doi.org/10.1016/j.nima.2024.169551>

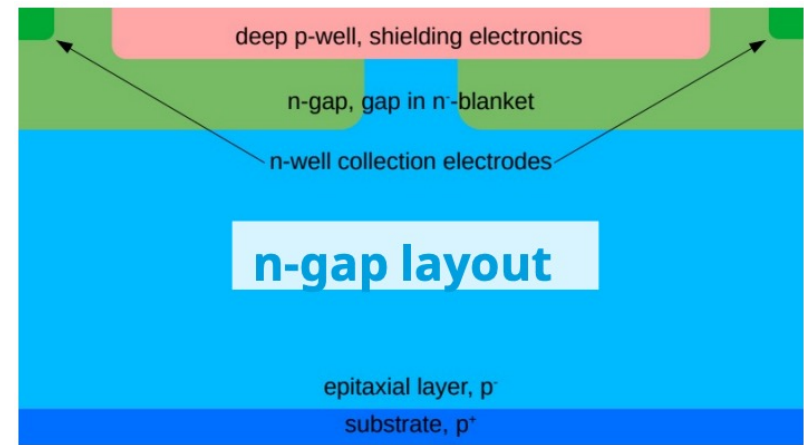
<https://doi.org/10.1016/j.nima.2023.168945>

65 nm MAPS technology validation

TPSCo 65 nm ISC CMOS imaging process validation for HEP

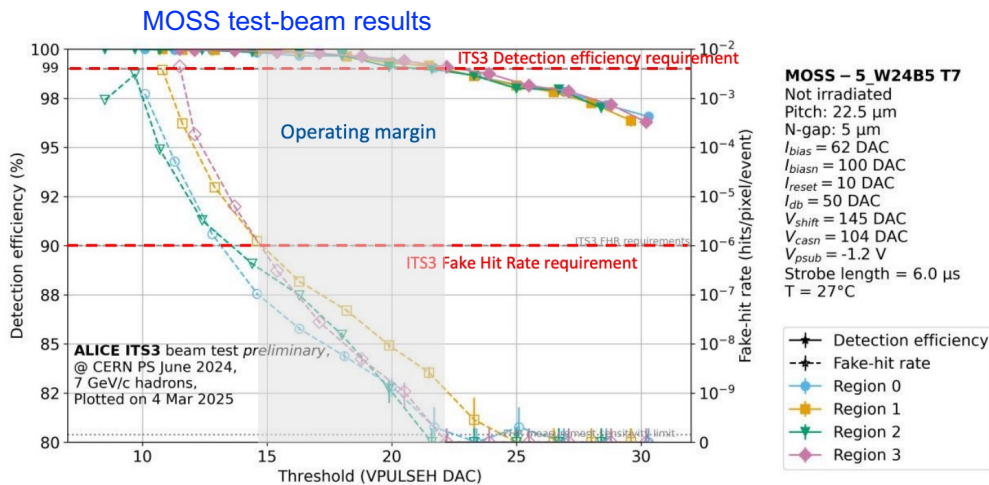
- 10 μm epitaxial layer, 7 metal layers, 300 mm wafers with stitching
- Collaboration CERN EP R&D, ALICE ITS3, DRD3/7, many institutes + other projects
- Small feature size \rightarrow small pixels ($\sim 10\text{-}35 \mu\text{m}$), enhanced performance
- Encouraging results from common MLR1 and ER1 productions in 2021-22:
 - Common submission of technology demonstrators from various groups
 - Stitched sensors (MOSS/MOST) for ALICE ITS3
 - Successful large-scale testing + simulation campaigns
 - Process modifications and sensor-design optimizations proven to work as expected
 - \rightarrow Full efficiency, $<100 \text{ ps}$ sensor timing for optimized designs, up to $10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$
 - \rightarrow Feasibility of stitching for wafer-scale sensors
 - \rightarrow Feasibility of porting hybrid r/o architecture to monolithic process (H2M)
 - \rightarrow Thinning to $<20 \mu\text{m}$ w/o performance loss
- Candidate technology for ALICE3 and FCC-ee vertex developments

Small-collection-electrode sensor layout in TPSCo 65 nm



<https://indico.cern.ch/event/1581713/contributions/6763822>

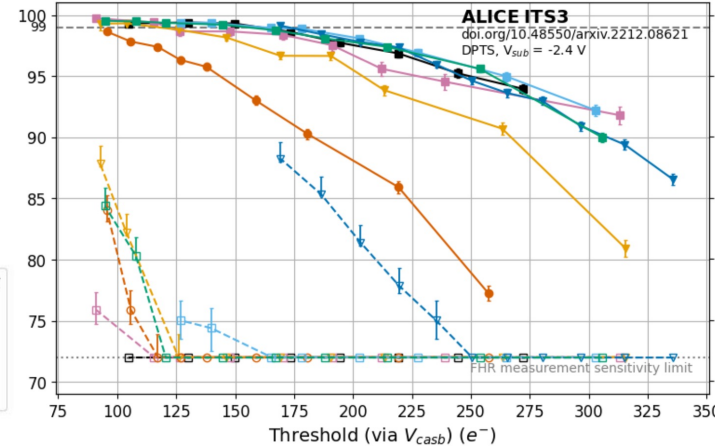
Comprehensive review of 65 nm results: *F. King et al.*, <https://doi.org/10.1016/j.nima.2026.171672>



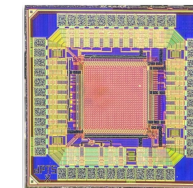
MOSS - 5 W24B5 T7
 Not irradiated
 Pitch: 22.5 μm
 N-gap: 5 μm
 $I_{\text{bias}} = 62 \text{ DAC}$
 $I_{\text{biasn}} = 100 \text{ DAC}$
 $I_{\text{reset}} = 10 \text{ DAC}$
 $I_{\text{db}} = 50 \text{ DAC}$
 $V_{\text{shift}} = 145 \text{ DAC}$
 $V_{\text{casn}} = 104 \text{ DAC}$
 $V_{\text{psub}} = -1.2 \text{ V}$
 Strobe length = 6.0 μs
 $T = 27^\circ\text{C}$

- Detection efficiency
- Fake-hit rate
- Region 0
- Region 1
- Region 2
- Region 3

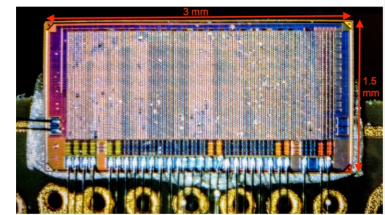
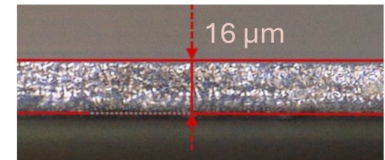
DPTS efficiency + fake-hit rate in test beam



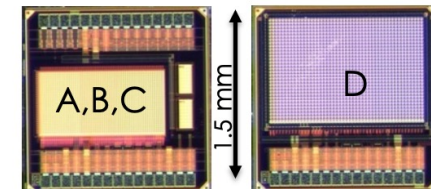
DPTS, 15 μm pitch, CERN



H2M, 35 μm pitch, DESY/CERN



CE-65, 15-25 μm pitch IPHC



- Detection efficiency
- Fake-hit rate
- Non-irradiated
- $10^{13} \text{ 1MeV n}_{\text{eq}} \text{ cm}^{-2}$
- $10^{14} \text{ 1MeV n}_{\text{eq}} \text{ cm}^{-2}$
- $10^{15} \text{ 1MeV n}_{\text{eq}} \text{ cm}^{-2}$
- 10 kGy
- 100 kGy
- 10 kGy + $10^{13} \text{ 1MeV n}_{\text{eq}} \text{ cm}^{-2}$

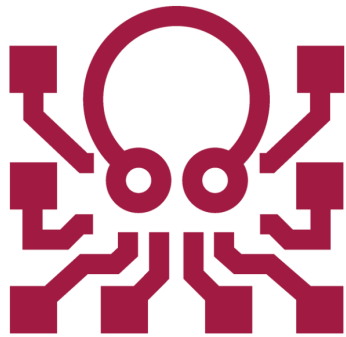
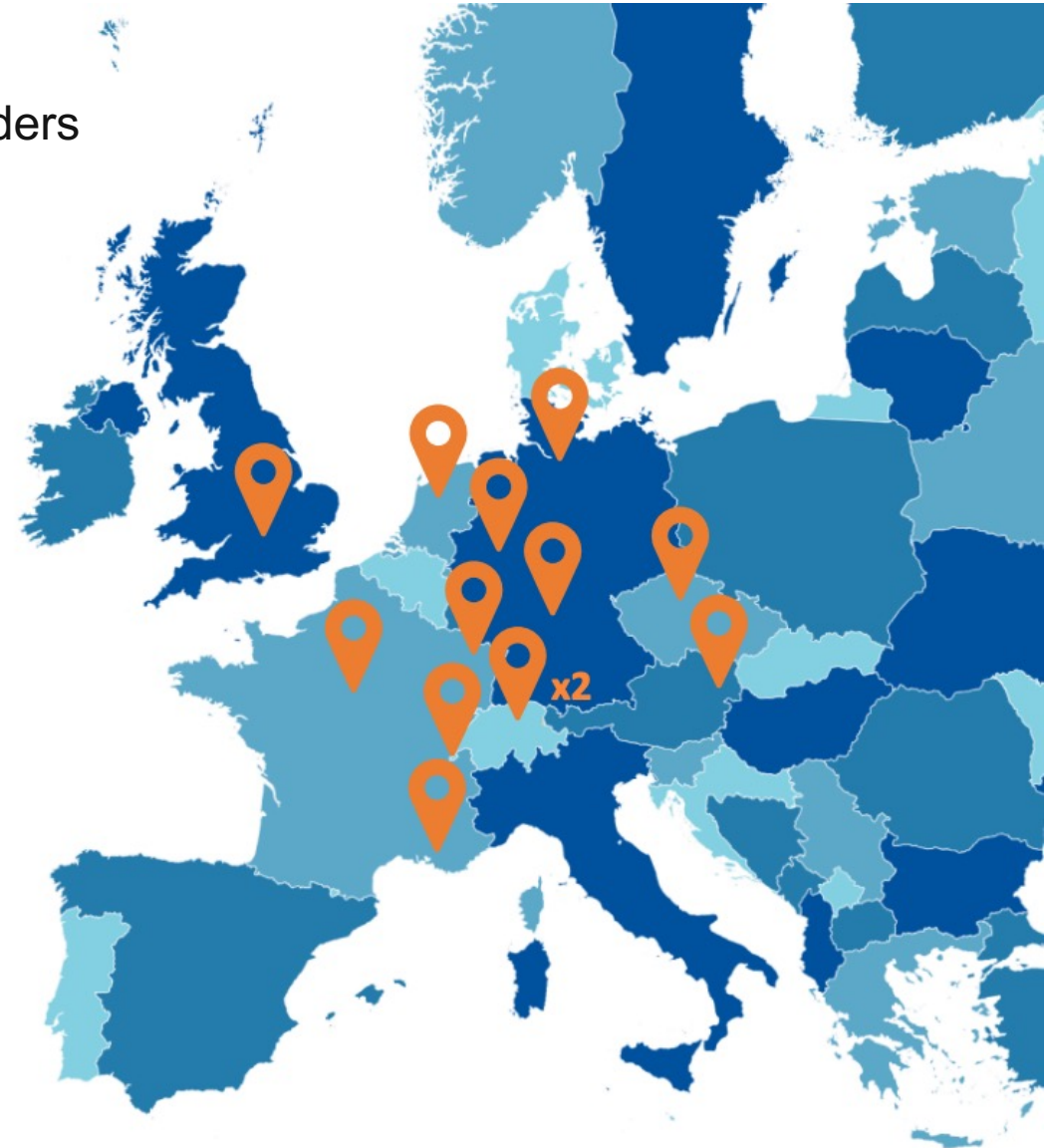
OCTOPUS 65 nm

OCTOPUS: Optimized CMOS Technology fOr Precision in Ultra-thin Silicon
(octopus.web.cern.ch)

- DRD3 R&D project towards vertex detectors for future lepton colliders
 - Intermediate target: sensors for **beam telescopes**
- Reticle-size CMOS sensor in **TPSCo 65 nm** process
- Full R&D chain performed by **13 institutes** across Europe
- First **test-chip submission** planned for Q4/2026 (ER3) in collaboration with **MANTA** tracker project

Member institutes

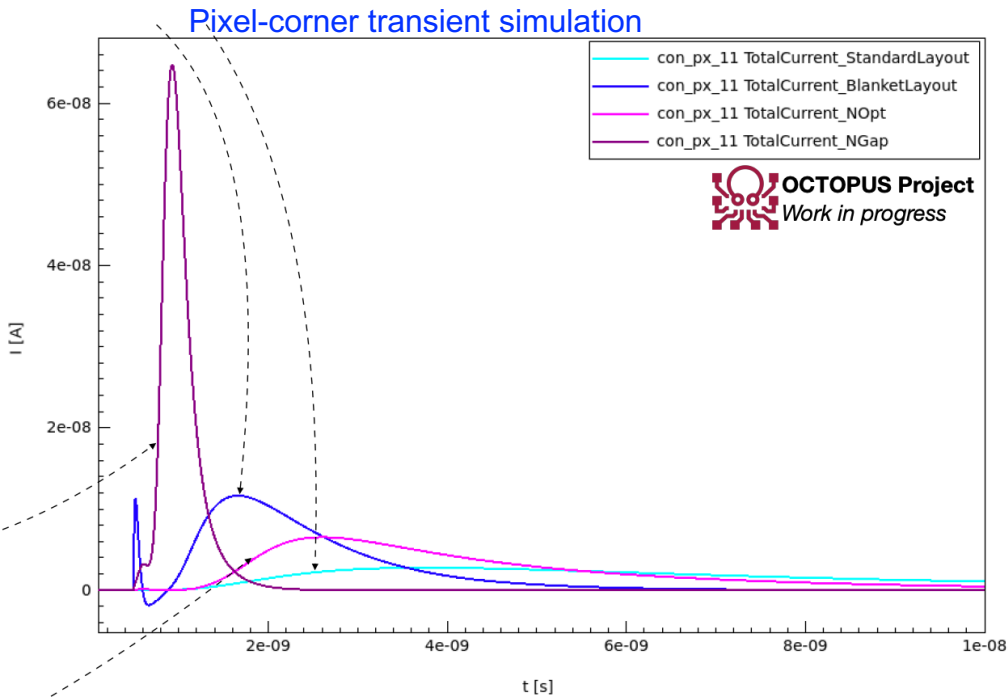
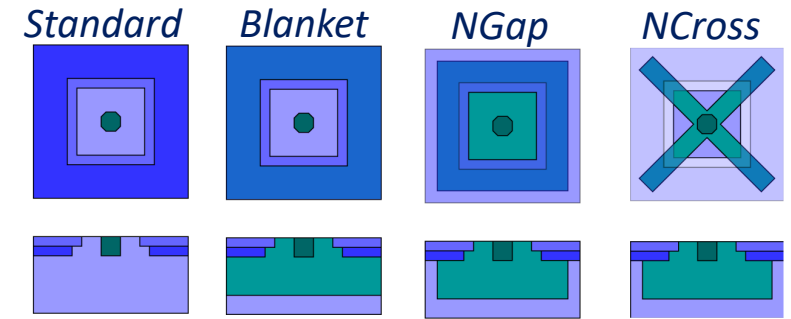
APC Paris	GSI Darmstadt
Universität Bonn	IPHC Strasbourg
CPPM Marseille	MBI Vienna
CERN Geneva	NIKHEF Amsterdam
DESY Hamburg	University of Oxford
ETH Zürich	Universität Zürich
FNSPE CTU Prague	



OCTOPUS sensor layout optimization

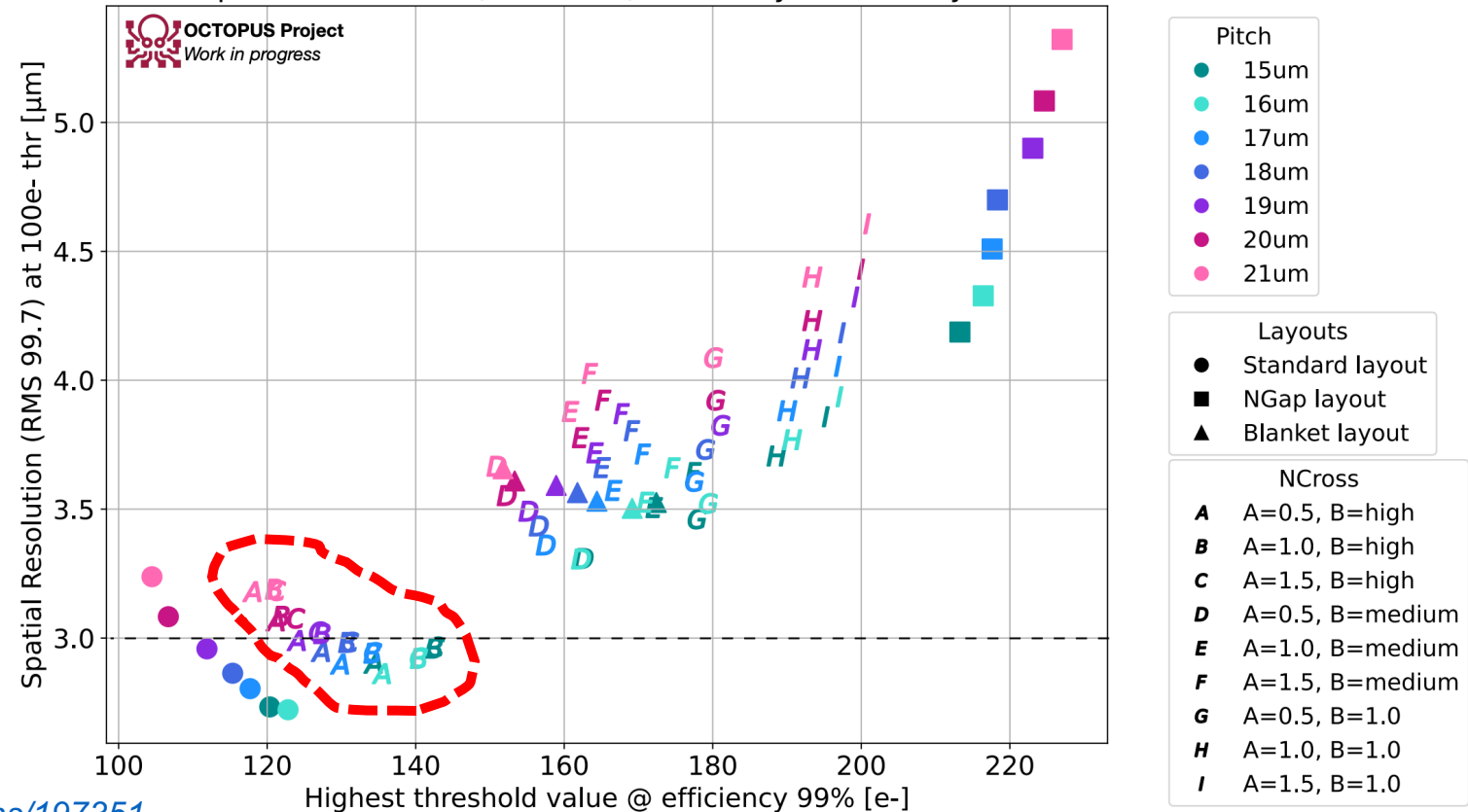
Sensor-design optimization with **TCAD** + **AllpixSquared** MC simulations

- Aim: **3 μm** resolution with full **efficiency** and few nanosecond **timing**
- Use results from existing TPSCo 65 test chips to benchmark simulations
- Large parameter space of process variants, pitch, ToT resolution
- Trade-off between: **charge sharing**, **efficiency**, **timing**
- Targets are in reach with **cross-shaped** implementation of deep N-layer in the **modified process (NCross)** for **18-20 μm** pitch



<https://indico.desy.de/event/51462/contributions/197351>

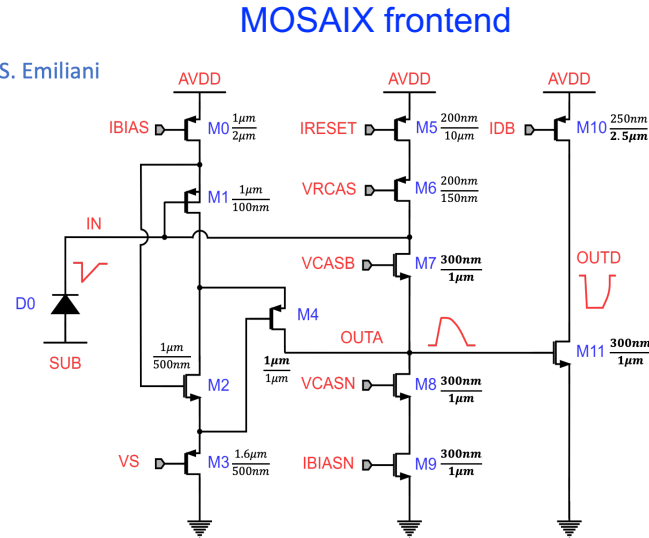
Spatial Resolution (RMS 99.7) vs T99 by Pitch & Layout



OCTOPUS ASIC design

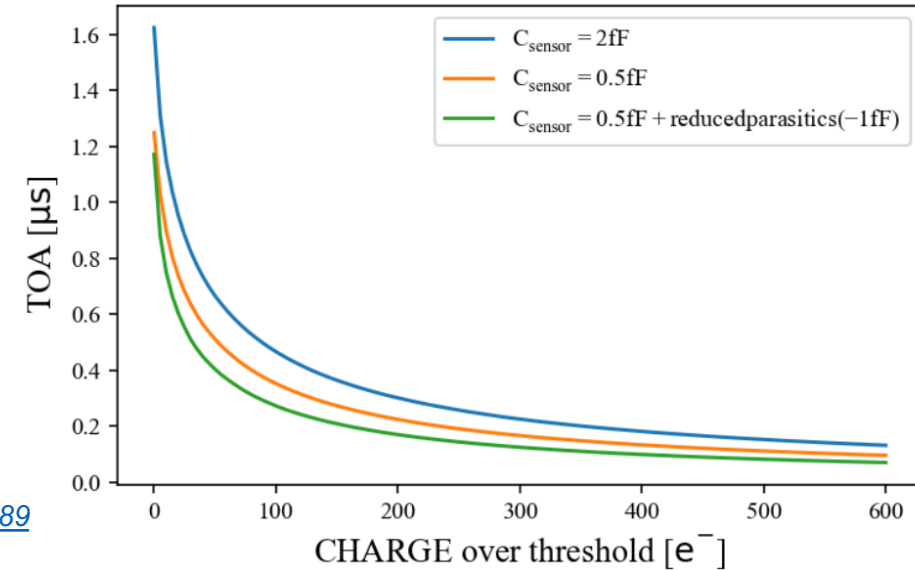
FE based on **MOSAIX** compact amplifier S. Emiliani

- Small footprint
→ Leaves space to place readout
- **Time-over-Threshold** measurement
→ correct for **time walk**
→ improve **spatial resolution** by **charge interpolation**
- Alternative designs also considered



<https://indico.cern.ch/event/1461789>

MOSAIX front-end time walk

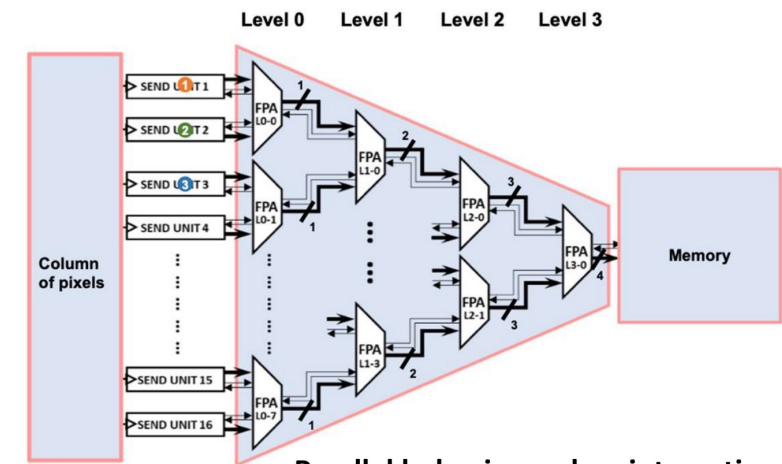


Asynchronous Priority Arbiter (APA) r/o scheme

- Pixel grouping and multi-column readout
- Data-driven hit readout through arbiter tree
- Compact scheme → fits in $\leq 20\mu\text{m}^2$ pitch
- **High-rate** readout at **low power**
- No clock in matrix (**TDC time stamping** in periphery)
- Resolution $< 5\text{ns}$ feasible
- 65nm proof-of-concept test chip **SPARC** (IPHC) currently under test

APA r/o architecture considered for OCTOPUS/MANTA

Asynchronous Priority Arbiter Tree



Parallel behavior and no integration time

<https://indico.desy.de/event/51462/contributions/197348/>

Conclusions + Outlook

- **Stringent requirements** for FCC-ee vertex detectors:
 - Precision physics needs
 - Environmental conditions
- All detector concepts include **MAPS** vertex detectors
- Currently only **few projects** dedicated to vertex-detector R&D
- **MAPS R&D projects** profit from advancements in semiconductor **industry** + **simulation-based process optimizations**
- Fulfilling all FCC-ee vertex requirements **simultaneously** remains challenging
 - Will require optimized designs in **advanced technology nodes**
 - **Synergies** with ALICE3 expected

Thanks to everyone who provided material for this talk!